



# The Coherent X-ray Imaging (CXI) Instrument at LCLS

#### Sébastien Boutet

SLAC National Accelerator Laboratory October 28, 2009







- LCLS
- Front-end optics
- Coherent X-ray Imaging (CXI) Instrument
  - Hutch
  - Diagnostics
  - Optical System
  - Sample Environment
  - Detector
- Summary









# **CXI** Capabilities



- CXI instrument not only designed for biological imaging
  - Suitable for imaging any object in forward scattering
    - Not suitable for Bragg geometry
      - XPP, XCS instruments at LCLS can be used for that
- Other techniques compatible with CXI
  - SAXS / WAXS
  - Protein crystallography
  - Nanocrystal studies
  - Solution scattering



#### **LCLS Source**



# LCLS energy range (fundamental) : 800 – 8265 eV 3<sup>rd</sup> harmonic up to 24.9 keV (1% of the fundamental) Repetition rate: 120 Hz

Parameter	Value	Value	Value	Value	Value	Units
Photon energy	24795	8265	6000	4000	2000	eV
Wavelength	0.05	0.15	0.21	0.31	0.62	nm
Source size (FWHM)	60	60	67	73	78	μm
CXI Hutch distance from undulator exit	385.5	385.5	385.5	385.5	385.5	meters
Source divergence (FWHM)	0.73	1.1	1.34	1.89	3.47	µrad
Pulse duration	~70	~70	~70	~70	~70	fsec
Number of photons	1.7E+10	1.7E+12	2.7E+12	<i>4E+12</i>	8E+12	photons





- Soft X-ray Offset Mirror System (SOMS) selects 800-2000 eV range for soft X-ray line
- Hard X-ray Offset Mirror System (HOMS) reflects up to 25 keV.
- 385 mm clear aperture mirrors  $\rightarrow$  <70% transmission at 2 keV and >98% at 8.3 keV
- Offset mirror systems separate FEL beam from spontaneous background and removes high harmonics
- CXI instrument uses the hard x-ray branch
  - ~3-25 keV



#### Measured unfocused AMO beam

#### CXI Instrument at LCLS MID Workshop, ESRF, October 28 2009

#### Sébastien Boutet sboutet@slac.stanford.edu



## **LCLS Instruments**













#### Insert compact 0.1 micron system in empty drift space between 1 micron KB mirrors and focal plane



CXI Instrument at LCLS MID Workshop, ESRF, October 28 2009 Sébastien Boutet sboutet@slac.stanford.edu

# **Diagnostics and Common Optics**



XRT # FEH Hutch 5 Х

Guard Slits Diagnostics Photon Shutter Attenuators Pulse Picker Focusing Lenses Reference Laser Guard Slits Diagnostics Guard Slits

1 µm KB Mirrors

Diagnostics

**Guard Slits** 

0.1 µm KB Mirrors 0.1 µm Sample Environment Particle Injector Ion TOF-MS Detector Stage Guard Slits Focusing Lenses Diagnostics 1 µm Sample Environment Particle Injector Ion TOF-MS Detector Stage

Wavefront Monitor Beam Dump



Requirement	Device		
Remove X-ray beam halo	X-ray Guard Slits		
Tailor X-ray intensity	Attenuators		
Tailor X-ray repetition rate	Pulse Picker		
Characterize X-ray pulse intensity	Intensity Monitor		
Characterize X-ray spatial profile	Profile Monitor		
Characterize X-ray focus	Wavefront Monitor		
Tailor focal spot size to the sample	X-ray Focusing Lenses		



## **CXI** Reference Laser



Ħ XRT ŀ FEH Hutch 5

Guard Slits Diagnostics Photon Shutter Attenuators Pulse Picker Focusing Lenses Reference Laser Guard Slits Diagnostics Guard Slits 1 µm KB Mirrors Diagnostics Guard Slits

0.1 µm KB Mirrors 0.1 µm Sample Environment Particle Injector Ion TOF-MS Detector Stage

**Guard Slits** 

Focusing Lenses Diagnostics 1 µm Sample Environment Particle Injector Ion TOF-MS Detector Stage

Wavefront Monitor Beam Dump



- Purpose
  - Rough alignment of the experiment without the X-ray beam
  - Provides a visible line to align components
- Requirements
  - Useable with any part of the instrument vented to air
    - Window valves
  - Aligned to the unfocused FEL beam to within 100 microns



# CXI 1 µm KB Mirrors





Guard Slits Diagnostics Photon Shutter Attenuators Pulse Picker Focusing Lenses Reference Laser

Guard Slits

Diagnostics

Guard Slits

1 µm KB Mirrors

Diagnostics

**Guard Slits** 

0.1 µm KB Mirrors 0.1 µm Sample Environment Particle Injector Ion TOF-MS

**Detector Stage** 

**Guard Slits** 

Focusing Lenses Diagnostics

1 µm Sample Environment Particle Injector Ion TOF-MS Detector Stage

Wavefront Monitor Beam Dump



- Purpose
  - Produce a 1 µm focus
    - Focal lengths
      - 8.7 m for M1
      - 8.3 m for M2
  - Requirements
    - 350 mm clear aperture
    - 3.4 mrad maximum incidence angle
    - SiC coating
    - <1 nm rms height error over entire mirror</p>

2-11 kel/ energy range

KB focusing also provides harmonic rejection





#### **CXI Sample Chamber**



Sébastien Boutet

sboutet@slac.stanford.edu

**Photon Shutter** 

**Pulse Picker** 

Focusing Lenses

**Reference Laser** 

**Guard Slits** 

Diagnostics

**Guard Slits** 

1 µm KB Mirrors

Diagnostics

**Guard Slits** 

0.1 µm KB Mirrors 0.1 µm Sample Environment Particle Injector

**Detector Stage** 

**Guard Slits** 

**Focusing Lenses** 

1 µm Sample Environment **Particle Injector** Ion TOF-MS **Detector Stage** 

Wavefront Monitor Beam Dump

Position apertures and samples on grids

- Piezoelectric stages invacuum
  - 3 aperture stages for noise reduction
  - 5-axis sample stage for mounted samples
- **High Vacuum** 
  - 10<sup>-7</sup> mbar to minimize noise from air scatter
- Large exit flange for large detector
- Rapid access with large door
- Large volume for flexibility
- On-axis sample viewing
  - Using long-range microscope and mirror with hole
    - 2-3 micron resolution
- Multiple laser ports





#### **CXI Sample Chamber**



#### Front view

Back view





## **Sample Chamber Interior**





#### Many apertures are needed to measure signal at small angles

# LELS CXI Sample Chamber (Internal Views)

**Back view** 

Front view





#### **CXI** Detector



Ħ XRT FEH Hutch 5

**Guard Slits** Diagnostics **Photon Shutter** Attenuators **Pulse Picker** Focusing Lenses **Reference** Laser **Guard Slits** Diagnostics **Guard Slits** 1 µm KB Mirrors Diagnostics **Guard Slits** 0.1 µm KB Mirrors 0.1 µm Sample Environment Particle Injector Ion TOF-MS **Detector Stage Guard Slits Focusing Lenses Diagnostics** 1 µm Sample Environment **Particle Injector** Ion TOF-MS **Detector Stage** Wavefront Monitor

Collaboration with the Gruner Group at Cornell University



- 2D Pixel Array Detector
  - High resistivity Silicon (500 μm) for direct x-ray conversion.
  - Reverse biased for full depletion.
  - Bump-bonding connection to CMOS ASIC.
- <1 photon readout noise
- 110x110 µm<sup>2</sup> pixels
- 1520x1520 pixels
- 10<sup>3</sup> dynamic range
- 120 Hz readout

Tiled detector, permits variable 'hole' size

Beam Dump

# LCLS Detector Modules and Quadrant Rafts







Length: 6"

#### **Detector Partially Disassembled**

























## **Detector Stage**





- Center the detector hole on the direct beam
  - X, Y, Pitch and Yaw control
    - In-air motion of entire chamber
- Position the detector at the appropriate distance from the interaction region
  - Range along the beam : 50-2400 mm
    - Non-continuous
  - 500 mm travel range along the beam inside vacuum



#### Sample-detector distance flexibility is crucial

#### CXI Instrument at LCLS MID Workshop, ESRF, October 28 2009



# **CXI** Particle Injector





	particle beam	
•	<ul> <li>Non-synchronous particle arriv</li> <li>Requires highly concentrated</li> </ul>	al with the LCLS beam aerosol samples for high hit rate
•	<ul><li>Sample size range</li><li>10-1000 nm</li></ul>	
	Particle Inj	ector
nie	ector was designed for	or bio-molecules bu

Deliver support-free single particles to the LCLS beam

Aerodynamic lens technology to transfer aerosols to vacuum in a

was designed for bio-molecules but works for any type of sub-micron samples

Sample Chamber

> Sébastien Boutet sboutet@slac.stanford.edu

**CXI Instrument at LCLS** MID Workshop, ESRF, October 28 2009



#### **Aerodynamic Focusing**





Design is compatible with other technologies (droplet sources, aerojets)

## CXI 1 micron Sample Environment





### **CXI 0.1 µm KB Mirrors/Sample Environment**





CXI Instrument at LCLS MID Workshop, ESRF, October 28 2009

- Purpose
  - Produce a ~100 nm focus
    - Focal lengths
      - 0.9 m for M1
      - 0.5 m for M2
- Requirements
  - Identical to 1 micron KB System in every way except for the mirror curvature
- Integrated system with 0.1 micron Sample Chamber due to close proximity
- Separating sample from mirror environment is challenging with short working distances



#### Summary



- CXI instrument is designed for imaging of any submicron particles at near atomic resolution
- Sample environments are provided
  - Fixed targets
  - Injected samples
  - Plans to add cryo-cooled stage
- X-ray optics can tailor FEL parameters for users
  - 3 focal spot size : 0.1, 1 and 10 microns
    - Unfocused beam is possible
    - Possibility to refocus the beam for serial operation
  - Variable attenuation
  - Single pulse selection with pulse picker
  - Diagnostics on every pulse
- User operations start planned for early 2011
  - Website: <u>http://lcls.slac.stanford.edu/Instruments.aspx</u>





